

SENSOR AND METHOD OF CONTROLLING THE SAME

ABSTRACT

- 5 According to embodiments of the present invention, a sensor is provided. The sensor includes a substrate, a beam suspended from the substrate, and a plurality of conductive lines arranged on the beam, wherein the beam is adapted to be displaced in response to a current flowing through the plurality of conductive lines, and a magnetic field interacting with the beam, and wherein the sensor is configured to determine a property of the
- 10 magnetic field based on the displacement of the beam. According to further embodiments of the present invention, a method of controlling a sensor is also provided.

Figure 4A